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MEMS Inertial Device

Guest Editor:

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Deadline for manuscript submissions:
closed (31 July 2023)

Message from the Guest Editor

Dear Colleagues,

MEMS inertial device is the most widely used component of MEMS sensor, including MEMS gyroscope and MEMS accelerometer. It has the advantages of small size, light weight, low cost, mass production and good impact resistance. It has important application value and broad application prospect in national economy, national defense and military field. The development of the current information intelligent era has brought a new development opportunity for MEMS inertial devices, so that MEMS inertial devices have entered a new development stage of higher accuracy and higher reliability. Accordingly, this Special Issue seeks to showcase research papers, short communications, and review articles that focus on: (1)Microstructure optimization design of MEMS inertial device; (2) MEMS inertial device measurement and control system; (3) MEMS inertial device manufacturing technology; (4) Integrated application of MEMS inertial device.

We look forward to receiving your submissions!

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Message from the Editor-in-Chief

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